

Abstract

PYROTECHNIC MICROSYSTEM AND METHOD FOR FABRICATING A MICROSYSTEM

The invention relates to a microsystem and a method for fabricating a microsystem. The pyrotechnic microsystem (7, 1') comprises a substrate having at least two separate electrical initiation zones, each of which provides separate electrical initiation of a pyrotechnic material deposited on the substrate. This microsystem (7, 1') is characterized in that the same pyrotechnic material deposit (721, 721', 13) covers both initiation zones, said deposit (721, 721', 13) produced on the substrate having a thickness sufficiently small for the initiation of the pyrotechnic material in the initiation zone to remain localized and not propagate to the other initiation zone, but sufficient to generate a specific gas quantity.

Figure 3